

Anisotropic Damping in MEMS Oscillator

S. Silvestrini

Outline

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- 2. Model Definition
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- 4. Model Validation
- 5. Results and Discussion
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Introduction

- MEMS work in a significantly different environment with respect to larger size machine
 strongly affected by the surrounding air.
- The air presents a counter reactive force on the moving elements of such devices.



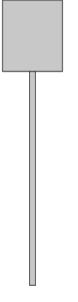
Introduction

 Damping effect of enveloping air is enforced if a plate is oscillating close to another plate, so that the air film is squeezed in between the two surfaces.

 It needs to vibrate with a high Q-factor in the horizontal plane and a low one along the transverse plane



Model Definition - Geometry



The model consists of one square proofmass suspended by a thin cantilever beam. The cantilever beam is fixed at the end to the surrounding environment.

Side [µm]	200
Length [μm]	600
Beam Width [μm]	20
Thickness [µm]	10



Model Definition – Coupling and Physics

The model uses <u>3D Solid-Mechanics Physics</u> interface to solve the squeezed film air/structure interaction using the <u>Thin-Film Damping</u> extension within the former domain.

Thin-Film Damping is a boundary physics, due to relative size with respect to the solid structure.

Zero-pressure thin-film edge condition used.



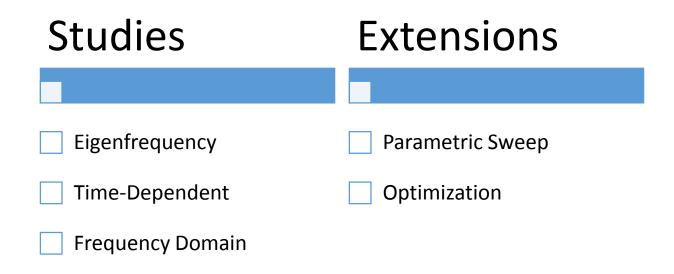
Model Definition – Material and Loads

- Solid Domain Silicon

Step response to a volume force: $F = \rho a$, where $a = \frac{g}{2}$, to study the oscillatory behaviour.



Use of COMSOL Multiphysics® Software



Thin-Film Damping boundary physics within 3D Solid Mechanics to simulate film/structure interaction.



Physics of the phenomenon can be described by *Reynolds equation*.

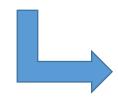
For small perturbations, and parallel motion, it can be rewritten as
$$\left(\frac{\partial u}{\partial x}\right) + \frac{\partial v}{\partial y} = \frac{\partial u}{\partial x} \left(\frac{\partial u}{\partial y}\right) + \frac{\partial v}{\partial y} \left(\frac{\partial u}{\partial$$

$$p_a \left(\frac{\partial^2 p}{\partial x^2} + \frac{\partial^2 p}{\partial y^2} \right) - \frac{12\mu\omega l^2}{h_0^2} \frac{\partial p}{\partial t} = \frac{12\mu p_a}{h_0^3} \frac{dh}{dt}$$



Cut-off frequency:
$$\omega_c = \frac{\pi^2 h_0^2 p_a}{12\mu w^2}$$

When a device owns a resonance frequency lower than the cut-off one



Viscous damping constant Elastic damping negligible



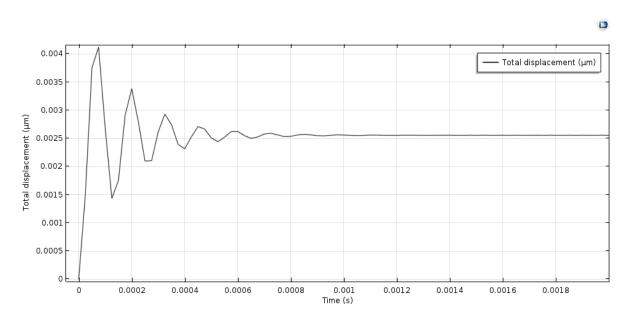
Standard second-order oscillator differential equation:

$$m\ddot{z} + c_d\dot{z} + (k_0 + k_e)z = \rho a$$

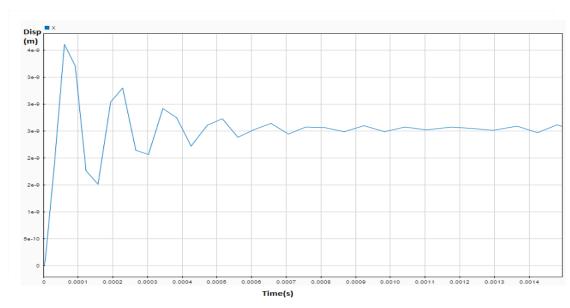
Where
$$c_d = 0.42 \frac{\mu L w^3}{h^3}$$
, $k_e = 0$ and $k_0 = \frac{3EI}{l^3}$.



Comsol simulation

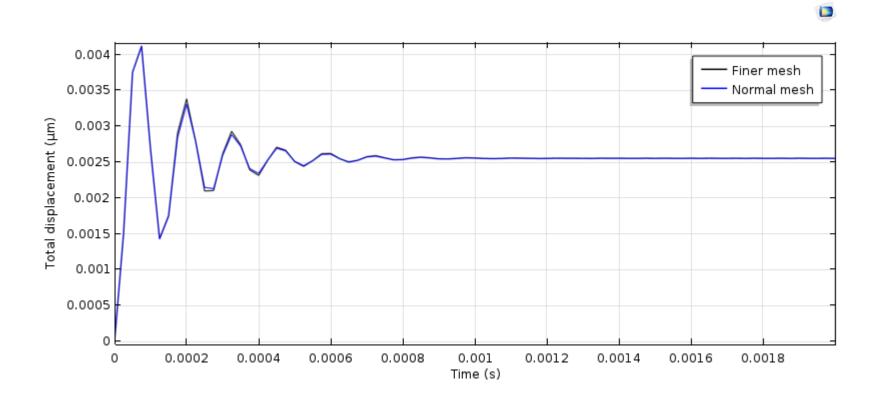


Differential-equation integrator



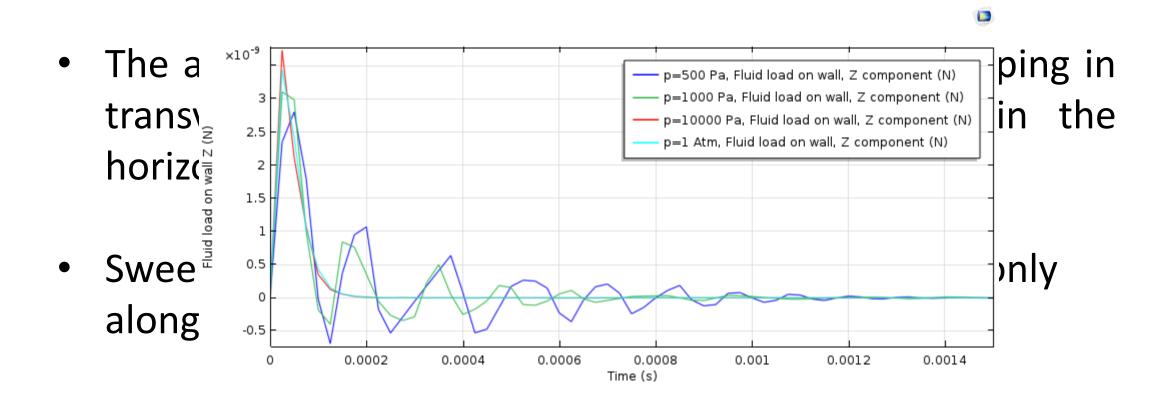


Mesh convergence test: *extra fine* ← *normal*





Results and Discussion – Pressure sweep





Results and Discussion – Pressure sweep

Clearly the smaller the ambient pressure, the less significant is damping.



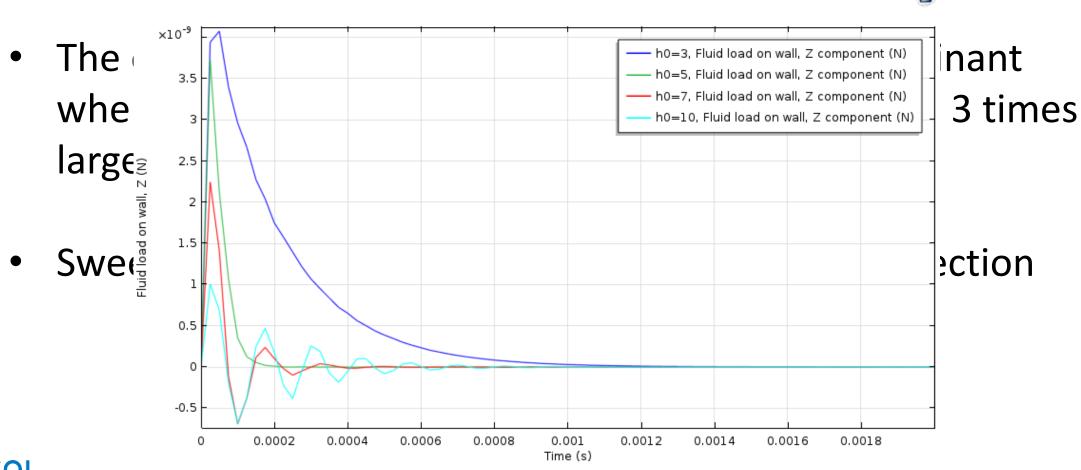
The ambient pressure should be kept relatively high in order to exploit thin-film damping to block the transverse oscillation.





10 kPa asymptotic behavior

Results and Discussion – Gap height sweep





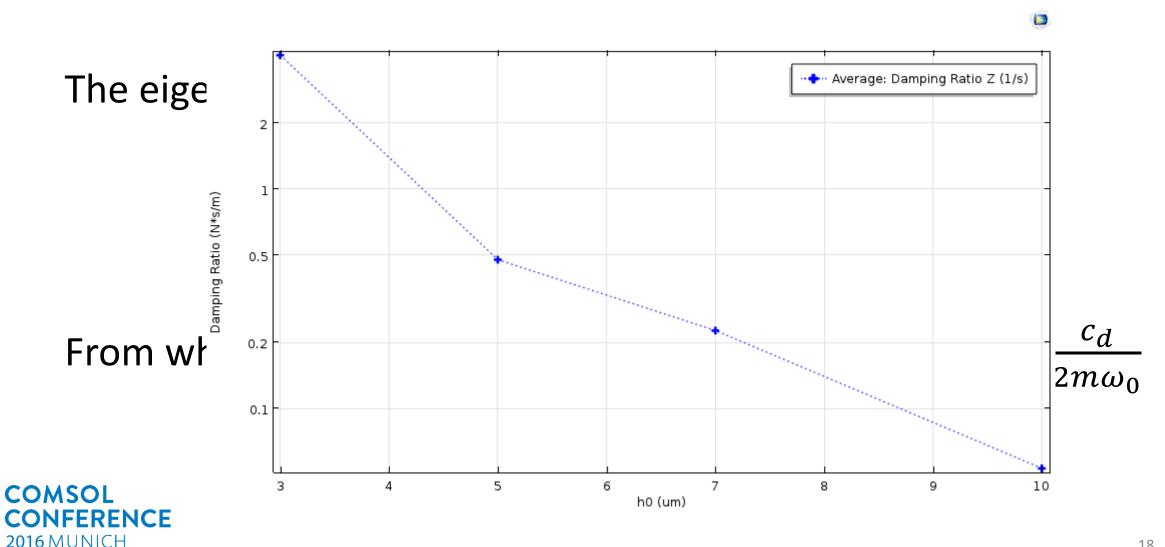
Results and Discussion – Gap height sweep

From a graphical interpretation:

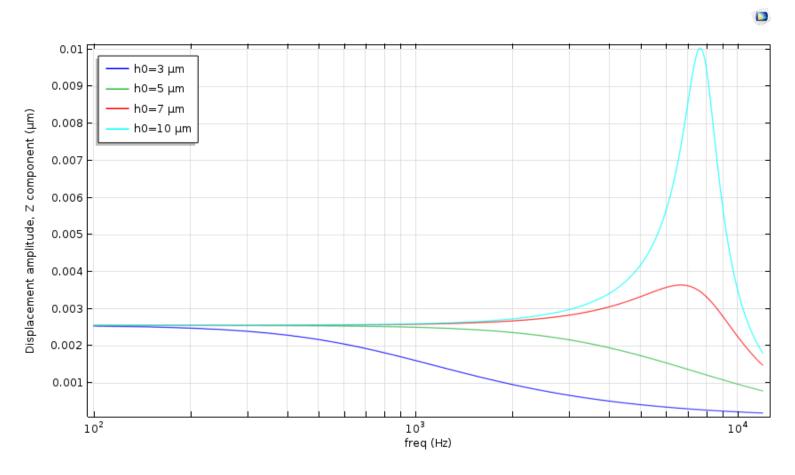
- Overdamped for $h = 3 \mu m$
- Nearly Critically damped for h = 5 μm
- **Underdamped** for $h = 7,10 \mu m$



Results and Discussion – Frequency Response



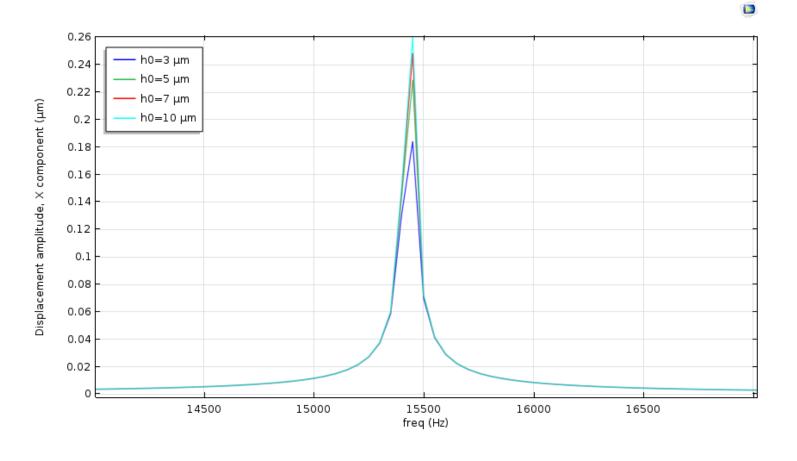
Results and Discussion – Frequency Response Z



The plot shows a typical set of second-order damped oscillator curves, as expected from the Time-Dependent study



Results and Discussion – Frequency Response X



Although each frequency response is typical of an underdamped system, the quality factor reduces as the gap height reduces.

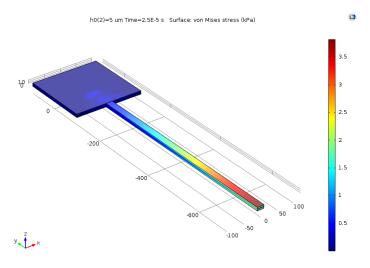


Results and Discussion – Frequency Response

- Not much damping is present in the horizontal motion along X
- Second-order damped oscillator curves along Z



Best-performing if critically damped along Z





Results and Discussion – Optimization

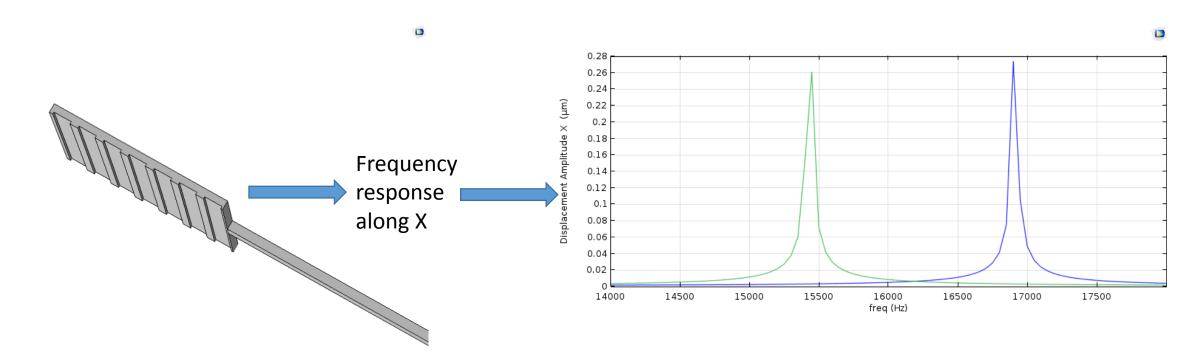
An Optimization study was added to a Time-dependent along the Z direction to find out the gap height that would force the system to be critically damped.

Nelder-Mead algorithm:
$$f(h) = \zeta_z - 1 \longrightarrow min(f)$$

$$h_{min} = 4.48 \mu m$$



Results and Discussion – Surface Texture Variation





Maximum amplitude is higher then the best-case of previous scenario

Conclusions and Future Work

Conclusions

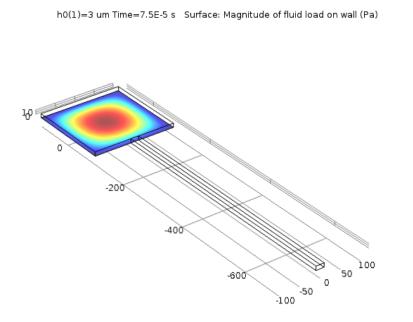
- Asymptotic behavior for pressure higher than 10 kPa
- Radial distribution of fluid load
- Major influence of thin-film thickness on Z damping
- Second-order oscillator along Z \longrightarrow critically damped as desired condition \longrightarrow $h_{min} = 4.48 \mu m$
- Model validation using analytical model

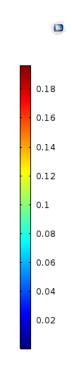
Future work

- Better modelling of the realistic MEMS environment (casing, etc)
- Topology optimization of the surface texture



Results and Discussion – Fluid Load





A typical radial distribution occurs, in which the inner fluid is trapped by the squeezing-effect resulting in a much higher reaction load on the wall.

